

34-31 “Development of an ultra-precision positioner and its applications”

電気システム工学科	教授	久保田	弘
大学院自然科学研究科	後期課程	永本	恵市
	前期課程	江頭	義也
電気システム工学科	学部学生	柴田	節
東京テクノロジー		小坂	光二
東京テクノロジー		高田	真次
東京テクノロジー		岩淵	哲也

Along with the alternation of LSIs generation, many ultra-precision technologies should be developed for the sub- $0.1\mu\text{m}$ resolution positioner. Not only are the optical sources for the nano-scale patterning, but also the stage totally controlled by the ultra-precision positioner is significant. This study reports the application of the ultra-precision positioner to a high velocity stage for the sub- $0.1\mu\text{m}$ range, which conventional positioners couldn't attain.

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